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Exhibitor Introduction	LayTec is a major provider of in-situ and in-line optical metrology for thin-film processes. These metrology tools are used in a broad range of thin-film applications such as LED & laser production, power devices and transistors, thin-film photovoltaics, oxide and organic deposition as well as other large area deposition processes. LayTec's integrated metrology provides access to all key thin-film parameters in real-time – either in-situ, during the deposition process, or in-line. Also, in-situ metrology tools for dry etching have been added expanding LayTec's portfolio along the production chain. Beyond these integrated methods, LayTec also offers mapping solutions which ideally complement in-situ measurements by providing uniformity analysis of the deposited layers. The implementation of LayTec metrology systems in production processes significantly shortens development cycles and enables efficient quality control that helps to considerably reduce production and development costs.	
Exhibit Product	EpiX® Comprehensive 2D optical wafer mapping for advanced compound semiconductor manufacturing. EpiCurve® TT Combines wafer curvature measurements with emissivity-corrected pyrometry and growth rate/thickness measurements by three-wavelength reflectance. TRItion® Automated endpoint detection for plasma etching with multi-wavelength in-situ reflectometry.	